



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Akira SHIMOKOHBE et al.

Application No.: 09/556,795

Filed: April 25, 2000

For: A THIN FILM-STRUCTURE AND A METHOD FOR PRODUCING THE SAME

Group Art Unit: 2813

Examiner: Asok K. Sarkar

Docket No.: 106096

#8/B  
FILED  
JUN 19/01  
MAIL ROOM

AMENDMENT UNDER 37 C.F.R. §1.111

Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

In reply to the Office Action mailed March 1, 2001, please amend the above-identified application as follows:

IN THE ABSTRACT:

Please replace the Abstract with the attached Abstract hereto.

IN THE SPECIFICATION:

Page 3, between lines 3 and 6, insert a new paragraph as follows:

B1  
This invention addresses the above-mentioned problems by developing a new material constituting the thin-film structure and a method for producing them as follows:

Page 9, between lines 9 and 12, insert a new paragraph as follows:

B2  
In using an appropriate micro pin-driving machine such as a micro manipulator, the thin film may be directly deformed during the heat-holding through the micro pin attached to the machine after it is heated to the temperature of the supercooled liquid phase region.